

204403US0PCT

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF:

:

BERNARD ASPAR ET AL.

:

SERIAL NO: NEW US PCT APPLN.
(Based on PCT/FR99/02476)

: ATTN: APPLICATION BRANCH

FILED: HEREWITH

:

FOR: METHOD FOR PRODUCING A
LAYER OF MATERIAL EMBEDDED
IN ANOTHER MATERIAL

PRELIMINARY AMENDMENT

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

Prior to examination on the merits, please amend the above-identified application as follows.

IN THE CLAIMS

Please cancel Claims 1-21 and add the following claims:

- A1*
- 22. (New) A method for producing a layer of a first material embedded in a substrate comprising at least one second material, comprising the following stages:
- formation in said substrate, at the level of the desired embedded layer, and by a method excluding the formation of a porous layer, of a layer of microcavities intended to serve as centers of nucleation and volume accommodation to produce said first material in said second material,